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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

LLERA et al.

Application No: 10/776,477

Filed: Feb. 10, 2004

For: Method for Applying  
Downward Force on Wafer During CMP  
(Amended)

)  
) Group Art Unit: 3723

)  
) Examiner: Anthony Ojini

)  
) Atty. Docket No:

)  
) Date: Oct. 22, 2007

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450 on Oct. 22, 2007.

Signed: \_\_\_\_\_

AI Penilla

Request for Reconsideration

AF

Honorable Commissioner for Patents  
Alexandria VA 22313-1450

Dear Sir:

In response to the Final Office Action dated Aug. 22, 2007. The 2 month term to respond extends to Oct. 22, 2007, for expedited After Final Processing. Please enter this amendment and remarks.

**Amendments to the claims** are reflected in the listing of claims which begin on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.